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PATENT
8040-1052

IN THE U.S. PATENT AND TRADEMARK OFFICE

In re application of

Taishi KUBOTA et al.

Conf. 8011

Application No. 10/763,244

Group 2823

Filed January 26, 2004

Examiner T. Dang

MANUFACTURING METHOD OF SEMICONDUCTOR
DEVICE AND OXIDIZATION METHOD OF SEMICONDUCTOR
SUBSTRATE

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In compliance with Rules 1.97 and 1.98, and in fulfillment of the duty of disclosure under Rule 1.56, the accompanying documents, copies of which are attached to this statement, are made of record on the enclosed Form PTO-1449.

A concise explanation of the relevance of these items is that these references were cited by the Chinese Patent Office in the corresponding Chinese Application Serial No. 200410002455.X. A copy of the Chinese Official Action with an English translation in which they were cited are attached hereto.

Under the provisions of 37 CFR 1.97(e), the undersigned hereby certifies that each item of information contained in this Information Disclosure Statement was first cited in any communication from a foreign Patent Office in a

counterpart foreign application not more than three months
prior to the filing of this Statement.

Respectfully submitted,

YOUNG & THOMPSON



Robert J. Patch, Reg. No. 17,355
745 South 23rd Street
Arlington, VA 22202
Telephone (703) 521-2297
Telefax (703) 685-0573
(703) 979-4709

RJP/lk

May 8, 2006

**INFORMATION DISCLOSURE CITATION
IN AN APPLICATION**

(Use several sheets if necessary)

 Attorney Docket No.:
8040-1052

 Application No.:
10/763,244

 Applicant:
Taishi KUBOTA et al.

 Filing Date:
January 26, 2004

 Group Art Unit:
2823
U.S. PATENT DOCUMENTS

| Examiner Initial | Document Number | Date | Name | Class | Subclass | Filing date (if appropriate) |
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FOREIGN PATENT DOCUMENTS

| Examiner Initial | Document Number | Date | Country | Class | Subclass | Translation | |
|------------------|-----------------|------------|---------|-------|----------|-------------|----|
| | | | | | | Yes | No |
| | CN 1293452A | 05/02/2001 | CHINA | | | | |
| | CN 1392604A | 01/22/2003 | CHINA | | | | |
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

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EXAMINER:

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.

* Abstract provided for the Examiner's convenience